Effect of Different TiO₂ Preparation Techniques on the Performance of the Dielectric Bolometer Ba₀₆Sr_{0.4}TiO₃ as a Distance Sensor (Kesan Kaedah Penyediaan TiO₂ yang Berbeza Terhadap Prestasi Bolometer Dielektrik

Ba₀₆Sr_{0.4}TiO₃ sebagai Pengesan Jarak)

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ABSTRACT

In this study TiO₂ films have been prepared using two different techniques i.e. sol-gel and electron gun evaporation (e-gun) techniques. The films were annealed at 300, 350 and 400°C in air. The microstructure study using field emission scanning electron microscope and x-ray diffractometer showed nanometer grains size and only the film prepared by sol-gel and annealed at 400°C has anatase phase while others are amorphous. To study the effect of the films (as buffer layer) onto the dielectric bolometer $Ba_{0,6}Sr_{0,4}TiO_3$ as distance sensor, sensors with the configuration of Al/BST/TiO₂/RuO₂/SiO₄/Si were built. Two different measurements i.e. with and without infrared source were carried out to measure the sensitivity and repeatability of the sensors. The sensors which contained sol-gel TiO₂ films gave reading for both type of measurements, indicating that the sensor can act as active and passive sensors. However, the sensors which contained e-gun TiO₂ films only gave responses when the IR source was used, indicating that they can only act as passive sensors. The most sensitive sensor was TiO₂ film prepared by sol gel and annealed at 350°C. In general sensors which contained TiO₂ films prepared by sol gel showed good repeatability.

Keywords: Sol-gel; thin film; TiO,

ABSTRAK

Dalam kajian ini, filem TiO₂ telah disediakan dengan dua teknik yang berbeza iaitu teknik sol-gel dan penyejatan senapang elektron (senapang-e). Filem kemudiannya disepuhlindap pada 300, 350 dan 400°C dalam udara biasa. Kajian mikrostruktur menggunakan mikroskop elektron imbasan pemancaran medan (FE-SEM) dan pembelauan sinar-X menunjukkan kesemua filem mempunyai saiz butiran nanometer dan hanya filem yang disediakan dengan sol-gel dan disepuhindap pada 400°C mempunyai fasa anatas sementara yang lain adalah amorfus. Untuk mengkaji kesan filem tersebut (sebagai lapisan penimbal) ke atas bolometer dielektrik $Ba_{0.6}Sr_{0.4}TiO_3$ sebagai pengesan jarak, sensor dengan konfigurasi Al/BST/TiO₂/RuO₂/SiO₂/Si telah dibina. Dua pengukuran yang berbeza iaitu dengan dan tanpa punca inframerah telah dijalankan untuk mengukur kesensitifan dan kebolehulangan pengesan. Pengesan yang mengandungi filem TiO₂ sol-gel memberikan bacaan untuk kedua-dua jenis pengukuran, menandakan pengesan ini boleh bertindak sebagai pengesan aktif dan pasif. Namun begitu, pengesan yang mengandungi filem TiO₂ sanapang-e hanya memberi tindak balas apabila punca inframerah digunakan, menandakan pengesan hanya boleh bertindak sebagai pengesan pasif. Pengesan yang mengandungi filem TiO₂ yang disediakan dengan sol-gel dan disepuhindap pada 350°C. Secara amnya pengesan yang mengandungi filem TiO₂ yang disediakan dengan sol-gel menunjukkan kebolehulangan yang baik.

Kata kunci: Filem nipis; sol-gel; TiO,

INTRODUCTION

Titanium dioxide (TiO_2) thin film is an interesting material as it has high dielectric constant and can be used in various applications such as high-density dynamic memory (Stamate et al. 2000), gas sensors (Garzella et al. 2000) and distance sensors (Dewi 2009; Hanani 2005). In a distance sensor which contains barium strontium titanate (BST) as an active layer, TiO₂ has been used as a buffer layer. Dewi (2009) and Hanani (2005) have reported on the performance of passive distance sensors which consist of BST as the active layer and micrograins TiO₂ as a buffer layer however their buffer layers were not being properly studied. Recently it has been reported that the microstructure and electrical properties of (Pb,Sr)TiO₃ ferroelectric films can be improved by controlling the TiO₂ buffer layer (Chen et al. 2008). The microstrucure and electrical properties of $Ba_{0.5}Sr_{0.5}TiO_3$ can also be improved by controlling La_2O_3 buffer layers (Fan et al. 2009). The TiO₂ buffer layer can be prepared using various methods such as radio-frequency(rf) sputtering, ionbeam sputtering, laser ablation, metal-organic chemical vapor deposition, electron gun evaporation and sol-gel technique. However, sol-gel technique has become famous compared will the other techniques because it needs only low cost apparatus and its ability to produce high purity and homogen samples (Tsuzuki et al. 1998; Wu et al.

2000). The sol is made of solid particles of diameter of few hundreds nanometer suspended in a liquid phase. Then the particles are condensed in a new phase (gel) in which the solid macromolecule is immersed in a liquid phase (solvent) (Brinker et al. 1990). To transfer the gel into thin film form, two techniques can be used i.e. dipping and spin coating techniques. The electron gun evaporation technique (e-gun) is a form of physical vapor deposition. In this technique, the target material is bombarded with high energy electrons under high vacuum, resulting in formation of plasma. This plasma is then collected onto a substrate to produce thin film. In this study nano grains TiO, have been prepared using 2 different techniques i.e. sol-gel and e-gun techniques. The physical properties of the films were characterized and studied. Then the same films were used as buffer layers in dielectric bolometer Ba_{0.6}Sr_{0.4}TiO₃ sensors and the effect of the TiO₂ on the performance of the sensors was also investigated. To our knowledge, there is no report yet on the effect of these different TiO, preparation techniques (sol-gel and e-gun) on the performance of the dielectric bolometer $Ba_{06}Sr_{04}TiO_3$ as a distance sensor.

MATERIALS AND METHODS

The p-type silicon substrates were cleaned using acetone, methanol and distilled water. Then $SiO_2(150 \text{ nm})$ and RuO_2 (100 nm) films were deposited onto the substrates using electron gun evaporation technique. These substrates were used in both TiO₂ preparation techniques.

Titanium butoxide (1 mL) was disolved in 5 mL ethanol and stirred for 6 h at room temperature. Without stopping the stirring process, 0.3 mL ion free water and 0.4 mL hydrochloric acid were added to the solution. Then the stirring process was continued for another hour. The composition of the obtained gel was $Ti(OC_4H_9)_4:C_2H_5OH:H_2O:HCl = 1:26.5:1:1$. To transfer the gel into thin film form a spin coater was used. The

spinning rate was 2,500 rpm within duration of 30 s. All of the films were dried at 50°C in air for an hour in order to get rid of the solvent, followed by the annealing process at 300, 350 and 400°C for 30 min in air.

The microstructures of the films were studied using X-ray diffractometer (XRD) (Bruker D8 Advance) and field emission scanning electron microscope (FE-SEM) (model Supra 55VP). The FE-SEM was also used to measure the films thickness. As the annealing temperature increased, the films thickness also increased (Table 1).

To study the effect of the prepared TiO_2 films on the performance of the dielectric bolometer, $\text{Ba}_{0.6}\text{Sr}_{0.4}\text{TiO}_3$ (BST) were prepared on the films by sol-gel process. The detail of the BST preparation technique has been reported elsewhere (Dewi et al. 2009). Aluminium film (100 nm) which acts as the upper electrodes were deposited by e-gun technique. The final configuration of the sensor was Al/ BST/ TiO₂/RuO₂/SiO₂/Si.

 TiO_2 (0.25 g) was pressed into pellet form using hydraulic pump and was used as a target in the e-gun technique. Table 2 shows the preparation parameters. The thickness of the films follow the thickness of the sol-gel films.

Then the films were annealed at 300, 350 and 400°C for 30 min in air. Similar procedures were also applied to the e-gun films in order to investigate the effect of the e-gun films onto the performance of the dielectric bolometer.

RESULTS AND DISCUSSION

The XRD patterns of all of the films prepared using the sol-gel and e-gun techniques are shown in Figure 1. All of the films except the sol-gel film annealed at 400°C are amorphous. The sol-gel film annealed at 400°C has crystallized into an anatase phase. These results showed that all of the films need higher annealing temperature in order to be crystallined.

TABLE 1. The TiO₂ sol-gel films thicknesses measured by FE-SEM

Film thickness (± 0.1 nm)
190.0
218.1
222.8
230.1

TABLE 2. The e-gun preparation parameter for TiO_2 films

Parameter	Value
Power (watt)	120
Pressure ratio of Ar:O ₂	3:1
Thickness (nm)	190, 218.1, 222.8, 230.1
Distance between target and substrate(cm)	5
Pressure (Mbar)	$2.5 imes 10^{-5}$

The size of the films grains were measured using the FE-SEM. Figures 2 and 3 show the micrographs of the sol-gel and e-gun prepared films, respectively. The average values (Table 3) clearly show that both sol-gel and e-gun techniques were capable in producing films with nanometer grain size. All of the films showed that the thickness increased with the annealing temperature, which could be due to the increment of the grain size. However, film with the same thickness but produced by different technique have different grain size, in other word sol-gel technique produce films with smaller grains compared with the e-gun technique.

In order to investigate the effect of the TiO₂ films on the performance of BST distance sensor, $Ba_{0.6}Sr_{0.4}TiO_3$ films (~ 430 nm) were deposited using sol-gel technique onto the TiO₂ films followed by Al (~ 100 nm) using e-gun technique. The final configurations of the sensors were Al/BST/TiO₂/RuO₂/SiO₂/Si. The upper and lower electrodes were Al and RuO₂, respectively. Two different measurements i.e. with and without IR source were carried out in order to measure the farthest distance that the sensor can detect. The schematic diagram of the sensor setup is shown in Figure 4. Details of the setup have been discussed elsewhere (Efil et al. 2010). For the measurement with IR, the source was fixed throughout the measurement while the distance of the sensor was varied in a sraight line with respect to the IR source. The IR source was replaced by a piece of paper during the measurement without the IR souce. The results are tabulated in Table 4.

Sensors with sol-gel TiO₂ films gave reading for both type of measurements, indicating that the sensors can act as active and passive sensors. However, the sensors with e-gun TiO₂ films only gave response when IR source was used, indicating that the sensors can only act as a pasive sensor. The farthest distance i.e. 100 cm was measured using the sensor with TiO₂ film prepared by sol-gel and annealed at 350°C. The active layer of the sensor i.e. BST





FIGURE 1. X-ray diffraction patterns of TiO2 thin films prepared by sol-gel and e-gun techniques

FIGURE 2. FESEM micrographs of the films prepared using sol-gel technique, (a) as prepared, annealed at (b) 300, (c) 350 and (d) 400°C



FIGURE 3. FESEM micrographs of the films prepared using e-gun technique, (a) as prepared, annealed at (b) 300, (c) 350 and (d) 400°C

TABLE 3. The summary of the thickness and grain size of the
films prepared by sol-gel and e-gun technique

Preparation technique	Annealing temperature (°C)	Thickness (±0.1) nm	Average grain size (±0.1) nm
Sol gel	As prepared	190.0	13.2
	300	218.1	17.0
	350	222.8	18.1
	400	230.1	19.3
E-gun	As deposited	190.0	19.8
	300	218.1	21.6
	350	222.8	24.2
	400	230.1	25.2



FIGURE 4. Schematic set-up for measuring the sensitivity and repeatability of the sensors

TABLE 4. The summary of the average grain size, sensor sensitivity and repeatability (with and without IR source)

Preparation technique	Annealing temperature (°C)	Average grain size (±0.1) nm	Sensor sensitivity with IR source (±2) cm	Sensor sensitivity without IR source (±2) cm	Sensor repeatability with IR source (±2) cm	Sensor repeatability without IR source (±2) cm
Sol gel	As deposited	13.2	0 - 20	0-5	Bad	Bad
	300	17.0	0 - 110	0-10	Good	Good
	350	18.1	0-140	0-40	Good	Good
	400	19.3	0-100	0-15	Good	Bad
E-gun	As deposited	19.8	0-15	None	Good	None
	300	21.6	0-30	None	Good	None
	350	24.2	0-20	None	Good	None
	400	25.2	0	None	Bad	None

films were directly deposited onto the TiO_2 bufer layer. Smaller grains TiO_2 are closed pack and the distance between grains were small. Hence the possibility of the BST leaking to the buffer layer was small and thus the current leakage was also small. To confirm these we measured the current density of the sensors and the results are shown in Figures 5 and 6. Sensors with e-gun films showed higher current leakage compared with the sensors with sol-gel films. The repeatability of the sensors were also measured and Figure 7 shows the typical results. Table 4 summarises the results for all of the sensors. For the measurement with IR source, only sensor with the as prepared sol-gel film does not show good repeatability while others show good results. The sensors with sol-gel films annealed at 300 and 350°C also show good repeatability for the measurement without IR source.



FIGURE 5. Current density of TiO2 thin films prepared by sol-gel technique



FIGURE 6. Current density of TiO2 thin films prepared by e-gun technique



FIGURE 7. Typical results of the repeatability of the sensors with sol-gel TiO_2 (a) as prepared, annealed at (b) 300, (c) 350 and (d) 400°C

CONCLUSION

Both sol-gel and e-gun techniques were capable in producing films with nanometer size grains, however the sol-gel technique produced smaller grains films. Sensors with sol-gel TiO_2 can act as active sensors and also showed good repeatability. This could be due to the smaller grains in the film thus increasing the current density of the sensors. The farthest distance was measured by sensor with TiO_2 sol gel annealed at 350°C. This sensor also showed the best repeatability.

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